

EL 844051780

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09,388,826  
Filing Date ..... September 1, 1999  
Inventor ..... Weimin Li, et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... E. Kielin  
Attorney's Docket No. .... MI22-1208  
Title: Low k Interlevel Electric Layer Fabrication Methods

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56.  
Copies of the cited prior art references are attached. No admission is made regarding  
whether the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Date:

*Sep 25, 2001*

By:

*Bernard Berman*

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